



MultiLink SCARA Wafer Robot - Semiconductor Wafer Handling Robot

Kensington's Atmospheric MultiLink SCARA [Wafer Handling Robots](#) have addressed the needs for semiconductor wafer and quartz substrate handling for more than a quarter century. Key innovative features developed for semiconductor robot wafer handling : Through Beam Wafer Sensing; 300mm Edge-Grip End-Effector : Robot Self-Teach Functionality. MultiLink SCARA wafer robots are used across the semiconductor equipment spectrum : Metrology Systems; Deposition Systems; Etch Systems; Reticle Process Systems; Thermal Processing Systems.

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